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PRELIMINARY AMENDMENT
ACCOMPANYING THE FILING OF AN APPLICATION

APPLICANT(s): Yoko Watanabe et al.
ATTORNEY DOCKET NO.: 075834.00404
INTERNATIONAL APPLICATION NO.: PCT/JP03/08176
INTERNATIONAL FILING DATE: June 27, 2003
INVENTION: MASK AND INSPECTION METHOD THEREFOR AND
PRODUCTION METHOD FOR SEMICONDUCTOR
DEVICE
CUSTOMER NO.: 33448

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

TITLE OF THE INVENTION

Please amend the title of the invention to:

~~MASK AND INSPECTION METHOD THEREFOR AND PRODUCTION
METHOD FOR SEMICONDUCTOR DEVICE~~

MASK, METHOD OF INSPECTING THE SAME, AND METHOD OF
PRODUCING SEMICONDUCTOR DEVICE